

Form PTO 1449  
(Modified)U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY DOCKET NO.  
249687US2SERIAL NO.  
10/790,828

LIST OF REFERENCES CITED BY APPLICANT

APPLICANT  
Masakiyo MATSUMURA, et al.FILING DATE  
March 3, 2004

GROUP

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
MS	AM	2000-306859	11/02/2000	JAPAN (with corr. EP 1 047 119)		X
MS	AN	1 047 119	10/25/2000	EUROPE		
	AO					
	AP					

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)			
MS	AQ	C-H. OH, et al., Japanese Journal of Applied Physics, vol. 37, part 2, no. 5A, pages L492 - L495, "A NOVEL PHASE-MODULATED EXCIMER-LASER CRYSTALLIZATION METHOD OF SILICON THIN FILMS", May 1, 1998	
MS	AR	M. NAKATA, et al., Japanese Journal of Applied Physics, vol. 40, part 1, no. 5A, pages 3049-3054, "A NEW NUCLEATION-SITE-CONTROL EXCIMER-LASER-CRYSTALLIZATION METHOD", May 2001	
MS	AS	M. MATSUMURA, IDW '02 AMD5-1, pages 263-266, "ADVANCED LASER-CRYSTALLIZATION TECHNOLOGIES OF SI FOR HIGH-PERFORMANCE TFTs", 2001	
MS	AT	International Display Workshops, pages 1-6, "ADVANCED LASER-CRYSTALLIZATION TECHNOLOGIES OF SI FOR HIGH-PERFORMANCE TFTs", 2002	
MS	AU	M. MATSUMURA, Journal of The Surface Science Society of Japan, vol. 21, no. 5, pages 278-287, "PREPARATION OF ULTRA-LARGE GRAIN SILICON THIN-FILMS BY EXCIMER-LASER", May 2000	
MS	AV	K. INOUE, et al., The Institute of Electronics, Information and Communication Engineers Transactions, vol. J85-C, no. 8, pages 624-629, "AMPLITUDE AND PHASE MODULATED EXCIMER-LASER MELT-REGROWTH METHOD OF SILICON THIN-FILMS - A NEW GROWTH METHOD OF 2-D POSITION-CONTROLLED LARGE - GRAINS", August 2002	<input type="checkbox"/> Additional References sheet(s) attached
			Date Considered 10/02/2006

Examiner /Matthew Song/

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.